



Attorney's Docket No.: 8034 USA/W-C/W-C/HMM

PATENT

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In Re Patent Application of:

Christopher Laurent Beaudry, et al.

Application No: 10/736,007

Filing Date: December 15, 2003

For: SINGLE WAFER CLEANING  
METHOD TO REDUCE PARTICLE  
DEFECTS ON A WAFER SURFACE

Examiner: Duy V.N. Deo

Art Unit: 1765

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

*do not enter  
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**AMENDMENT AND RESPONSE**

Dear Sir:

This is in response to the Office Action mailed April 6, 2006. Applicant respectfully requests the Examiner to enter the following amendments and consider the following remarks.:

**FIRST CLASS CERTIFICATE OF MAILING**

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage in an envelope addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450

on July 31, 2006

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